

Radiation Damage + Towards a Rad-hard Sensor Design

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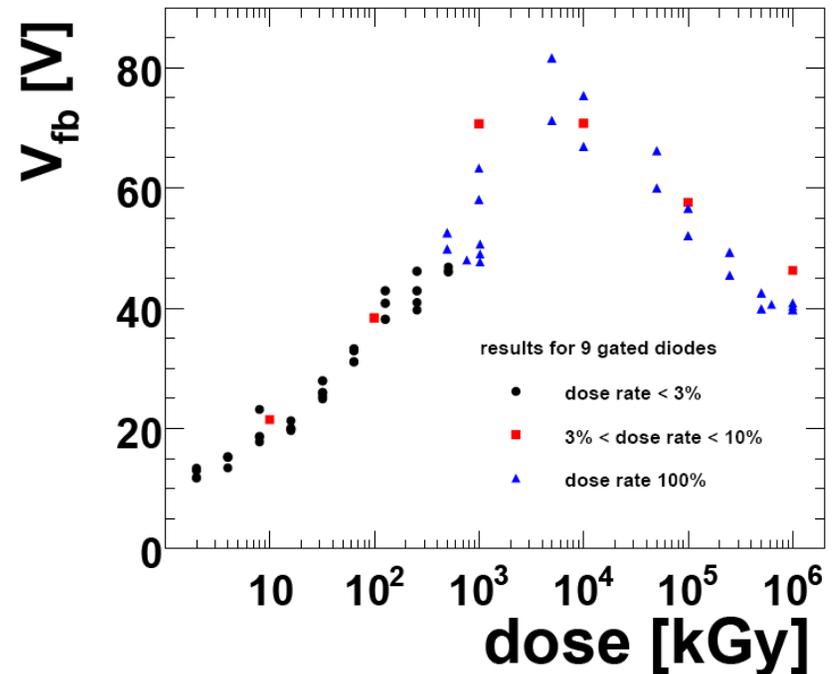
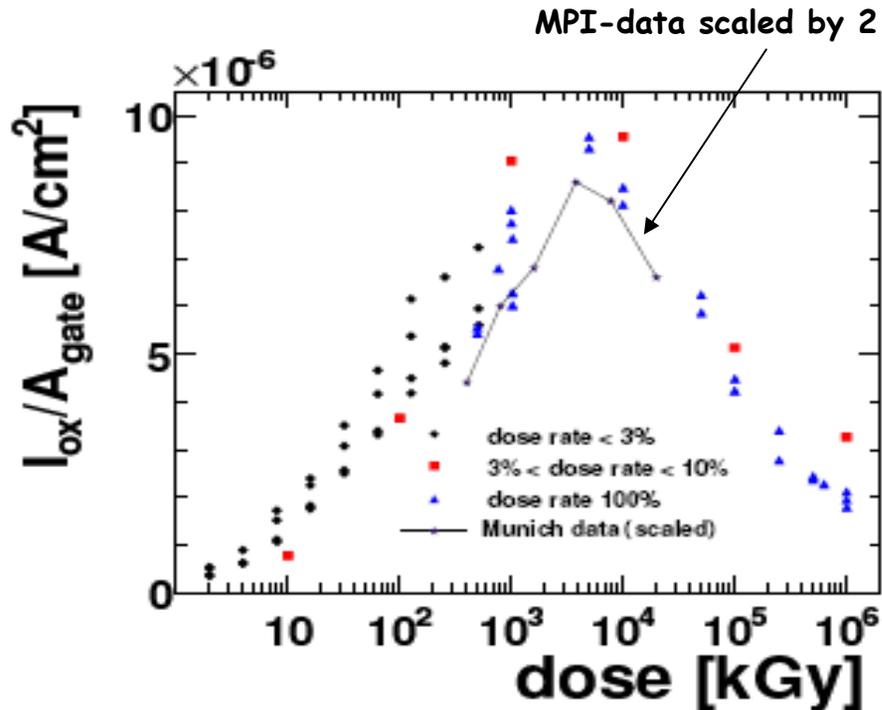
1. **Reminder: Summary of radiation damage measurements and parameter extraction for simulation**
2. **Sensor simulation: Sensor model, inclusion of radiation effects, first results**
3. **Next steps: Measurements and simulations**

1) has "left" radiation damage → moved early 2009 to 2nd thesis topic: precision measurement of the proton structure (as planned and promised at start of thesis)

2) new (16.7.09) PhD student from China - supported by EU (Marie Curie-ITN: MCPAD)

1. Summary of radiation damage measurements and parameter extraction for simulation (from gated diode measurements)

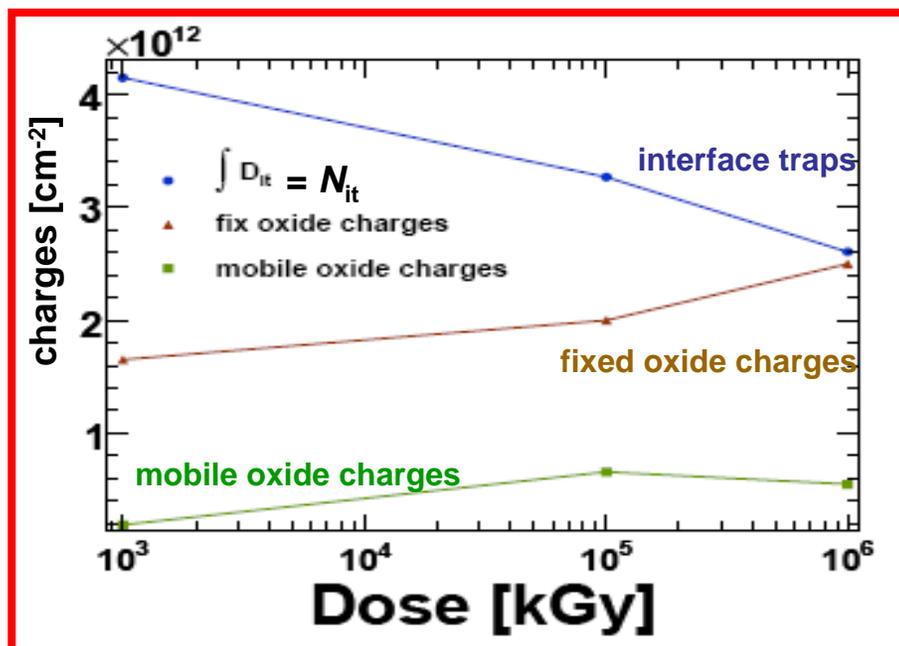
Surface generation current vs dose + "Flat-band voltage" vs dose (immediately after irradiation)



$\rightarrow V_{fb} [N_{Ox} + N_{it}]$ and $I_{Ox} [N_{it}]$ reach maximum at few MGy - then decrease
 (tentative conclusion: decrease due to N_{it} at high doses - reason not clear)

Relevant parameters:

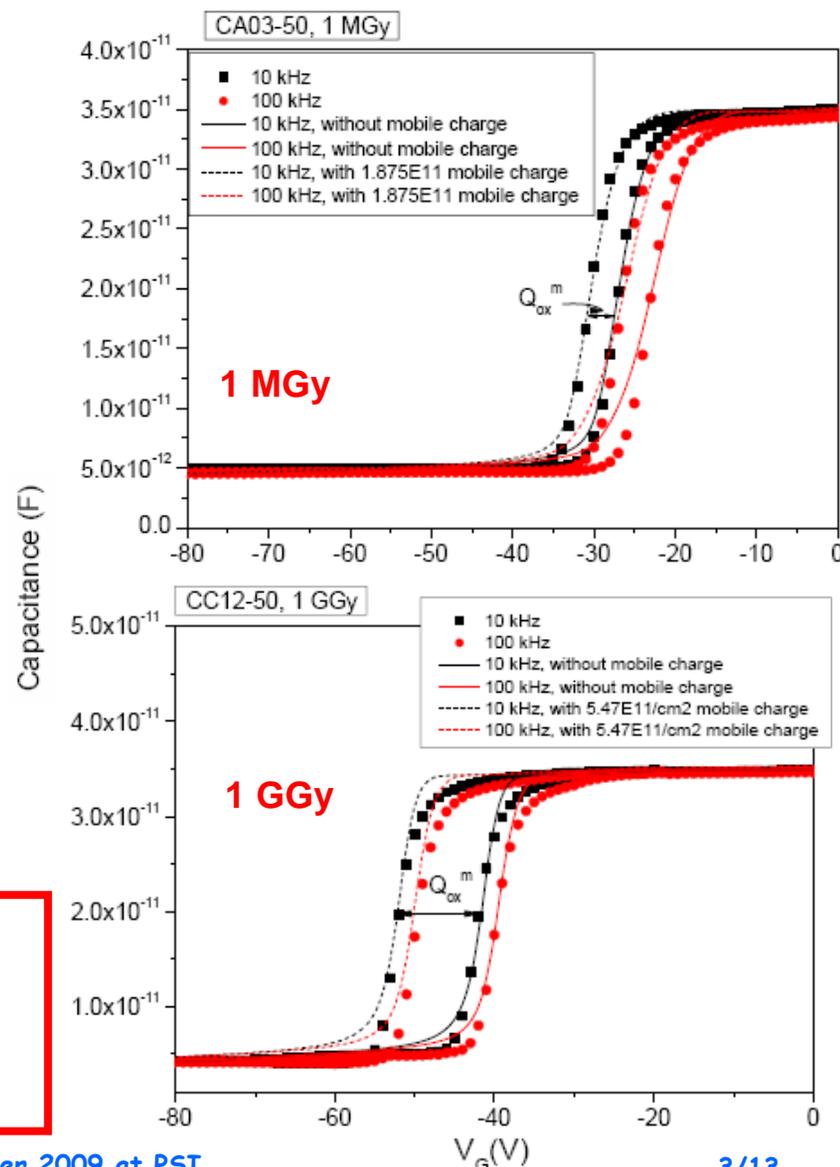
1. $N_{Ox}(fix)$ fixed oxide charges
2. $N_{Ox}(mob)$ mobile oxide charges - recent studies show introduction under biasing with long (hours) introduction time const.
3. $D_{it}[cm^{-2} \cdot eV^{-1}]$ interface trap density



→ summary:

→ data can be described by microscopic model → parameter extraction →
 → for use in simulations

Comparison to measurements



→ Impact of parameters on sensor performance

1. N_{Ox}^{fix} **fixed positive oxide charges** ← shift of ideal CMOS-C/V-curve
 - accumulation layer below oxide
 - strong electric fields causing breakdown

2. N_{Ox}^{mob} **mobile oxide charges** (close to interface) ← hysteresis C/V-curve
 - same effects as above; dependence **on time** + surface potential!

3. D_{it} **interface traps** (integral N_{it}) ← TSC (Thermally Stimulated Current)
 - current generation, if interface is exposed to E-field
 - contribution to surface charge density depends on
 - position of Fermi level
 - type of states
 - acceptors **compensate** positive oxide charges
 - donors **enhance** effect of positive oxide charges

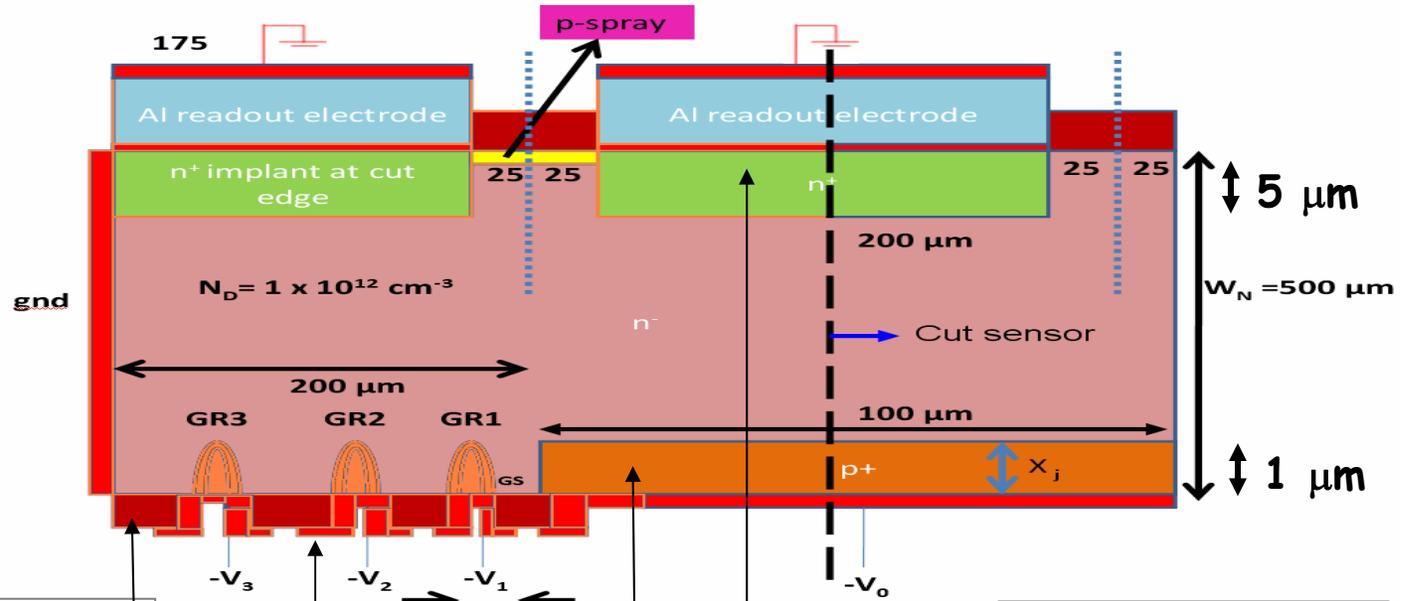
→ reliable simulation is not a simple task !

2. Sensor Simulation

Aim: optimise design for radiation hardness using the results of test structure measurements as input

1st project: breakdown and current for p⁺-n guard-ring structure

“generic sensor for first simulation”



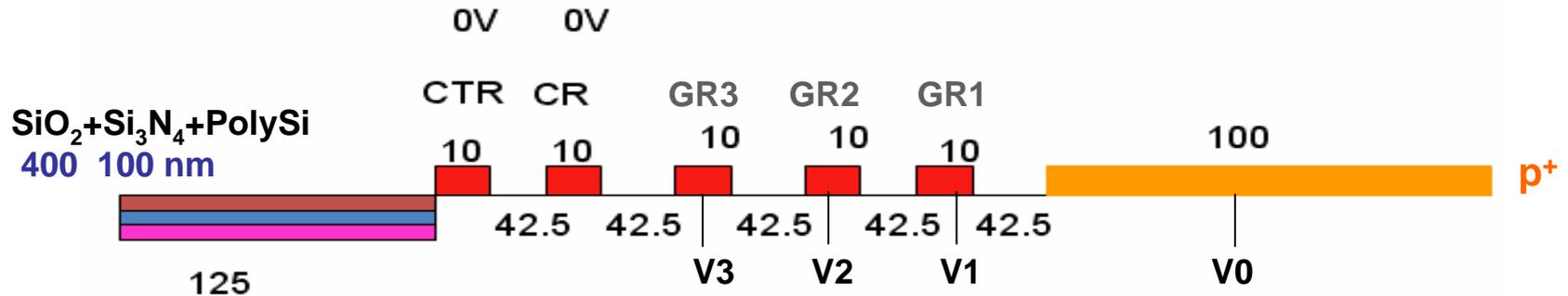
SiO₂+Si₃N₄: 400+100 nm
 p⁺-implant: 1 μm
 n⁺-implant: 5 μm
 metal overhang: 5 μm

n-doping: 10^{12} cm^{-3}
 thickness: 500 μm
 full depletion: 196 V
 I_{bulk} : 31 nA

"X-ray-entrance (p⁺)-side of generic sensor"

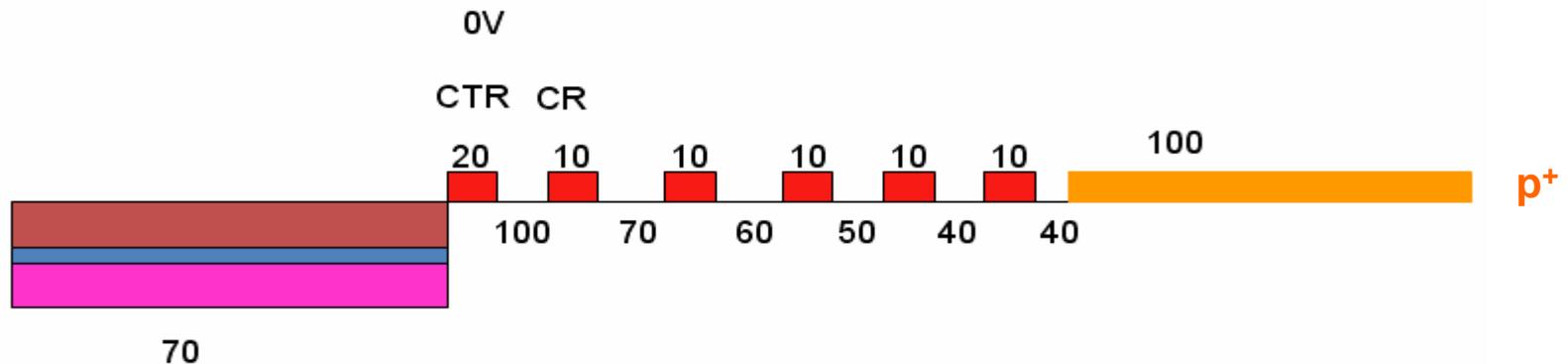
Layout of sensor **model I**

Simulation of 2-dim. cell of 487.5 × 500 μm²



Layout of sensor **model II**

Simulation of 2-dim. bcell of 600 × 500 μm²



CTR: Current Terminating Ring

CR: Current Ring

GRi: Guard Ring i

Program used: ISE-TCAD from Synopsis

Physical models used:

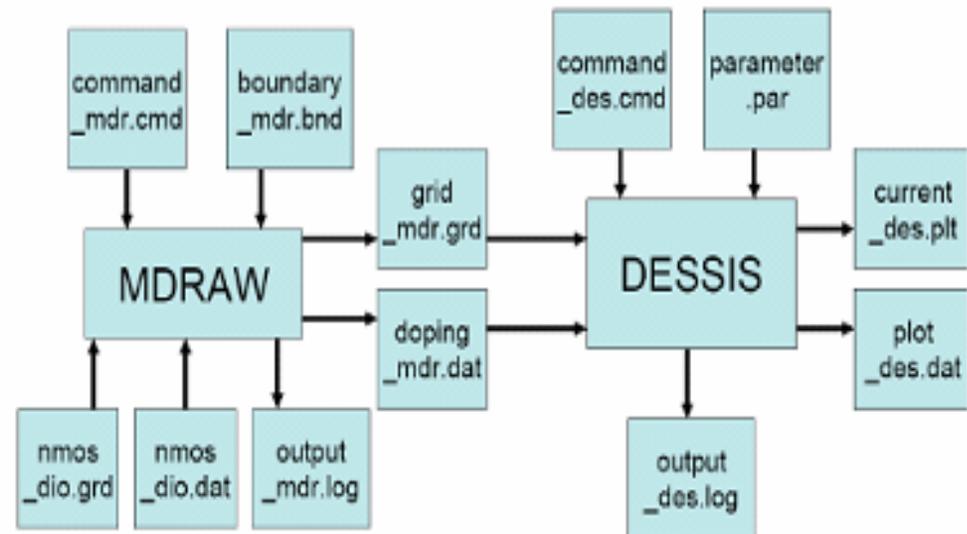
- SRH (Shockley-Read-Hall) recombination
- Auger recombination
- impact ionization
- trap models
- doping dependent mobility and high field saturation model, band to band tunneling
- surface recombination model

CPU time: 100 min
no. grid points: 60 000

Simulation procedure:

Procedure

- 1 Design structure in MDRAW
- 2 Feed results into DESSIS
- 3 Combine simulation of device (DESSIS) and circuit (SPICE)

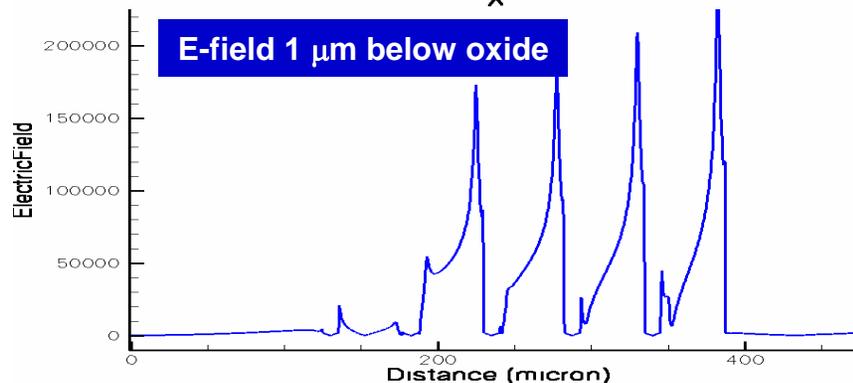
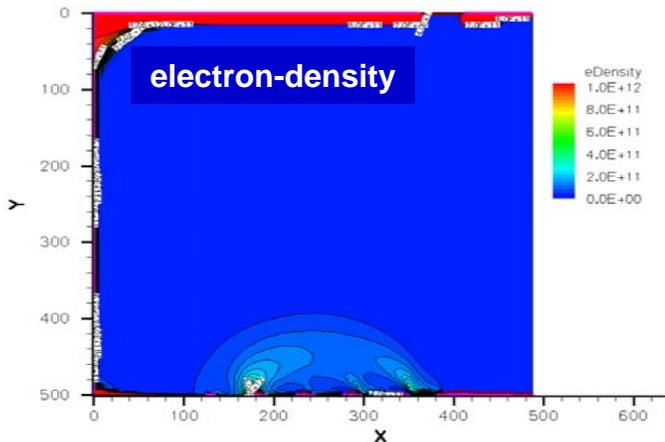
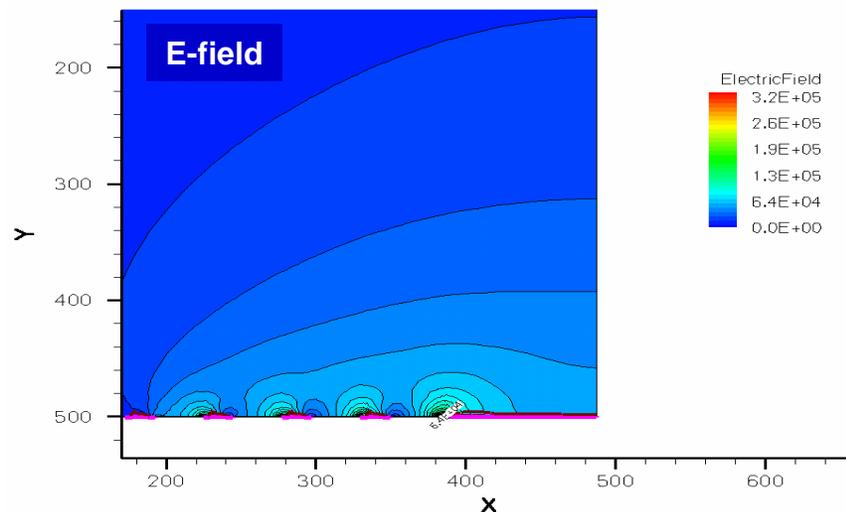
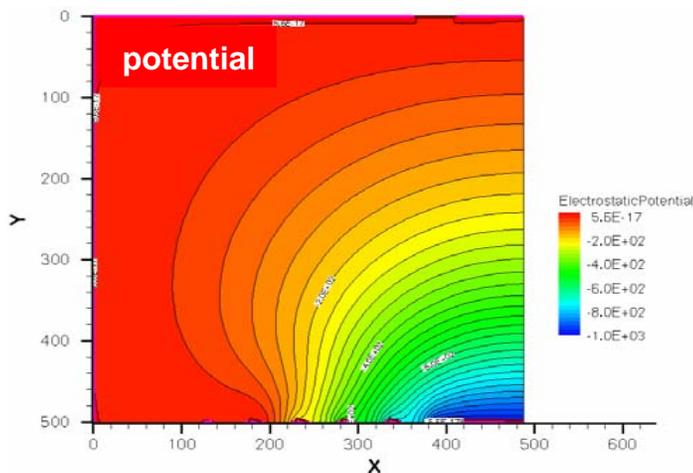


Break-down voltage vs. radiation damage

- "ideal case": $N_{Ox} = N_{it} = 0$ (to understand optimisation - sensor model I)

bias = V_0 , $V_1 = 0.75 \cdot V_0$, $V_2 = 0.5 \cdot V_0$, $V_3 = 0.25 \cdot V_0 \rightarrow$

- V_{bd} (break-down) > 1000 V
- optimized $V(GR) \rightarrow$ increase by ~10%

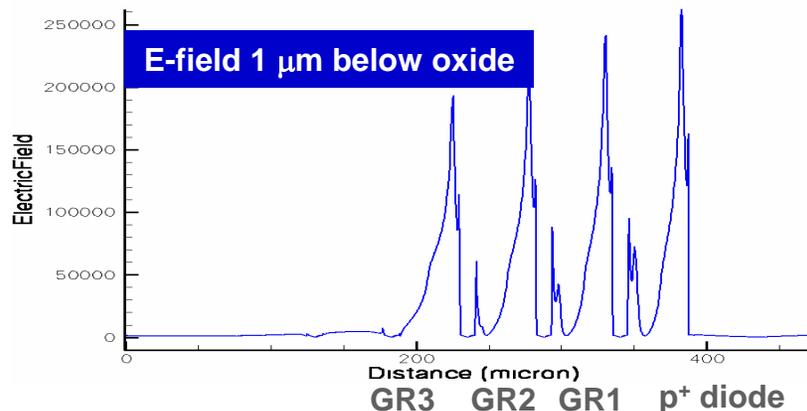
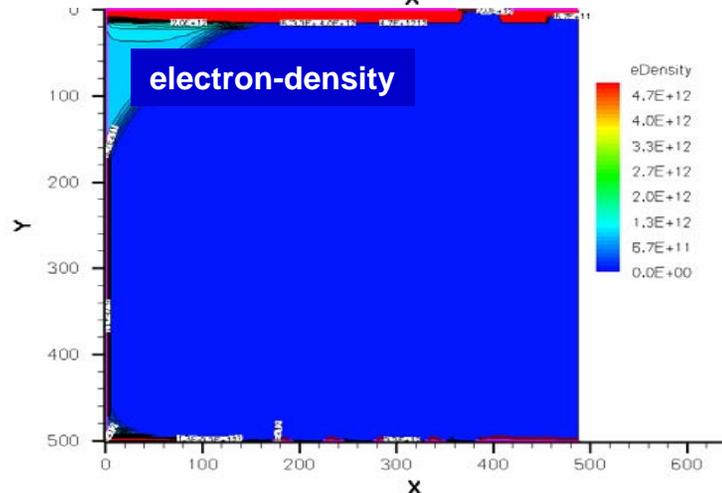
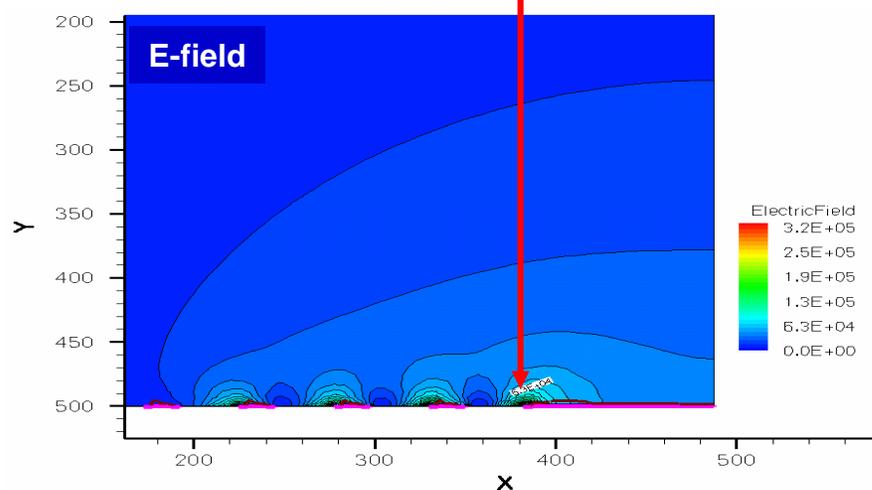
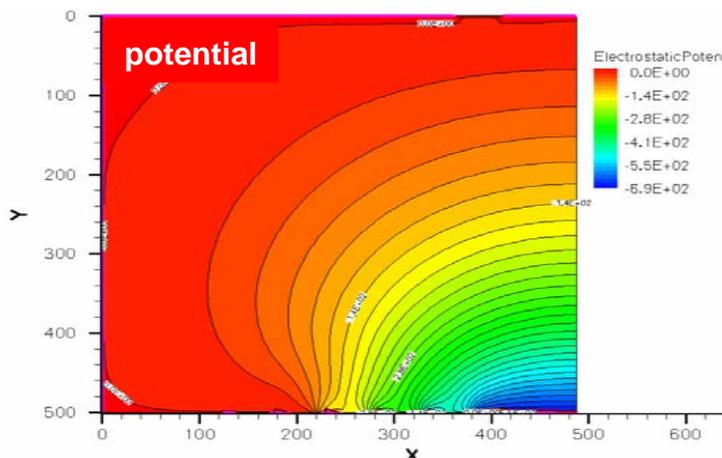


Break-down voltage vs. radiation damage

$N_{Ox} = 4 \cdot 10^{11} \text{ cm}^{-2}$ $N_{it} = 0$ (sensor model I)

bias = V_0 , $V_1 = 0.75 \cdot V_0$, $V_2 = 0.5 \cdot V_0$, $V_3 = 0.25 \cdot V_0 \rightarrow$

- V_{bd} (break-down) = **690 V**
- E_{max} below metal overhang (p^+)

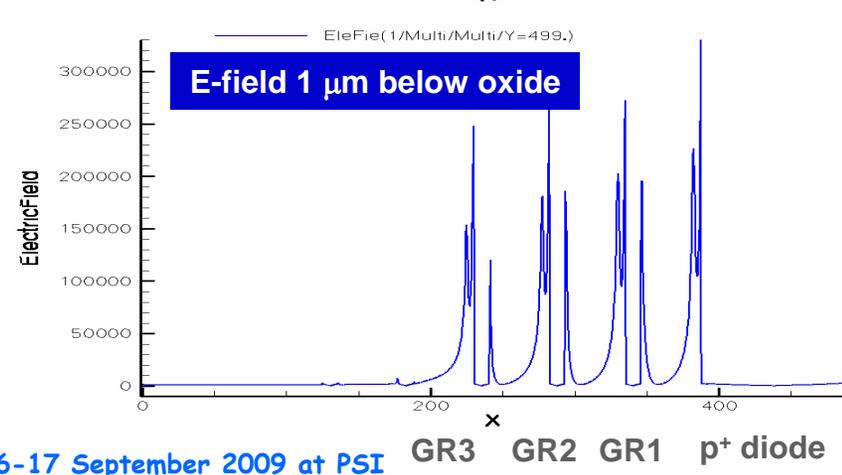
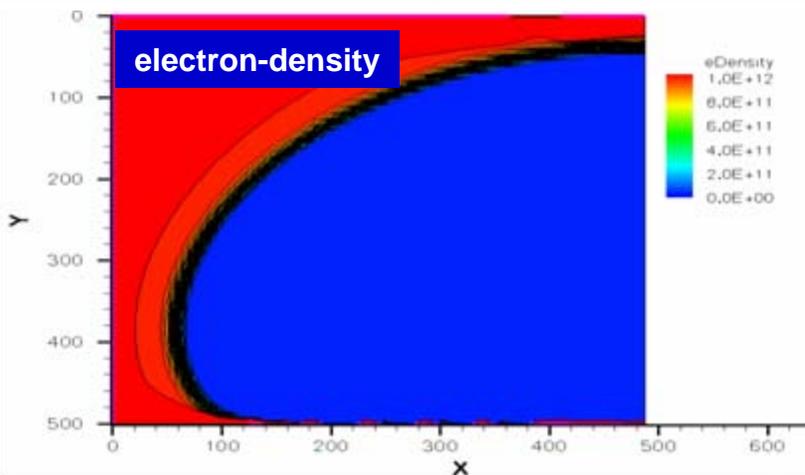
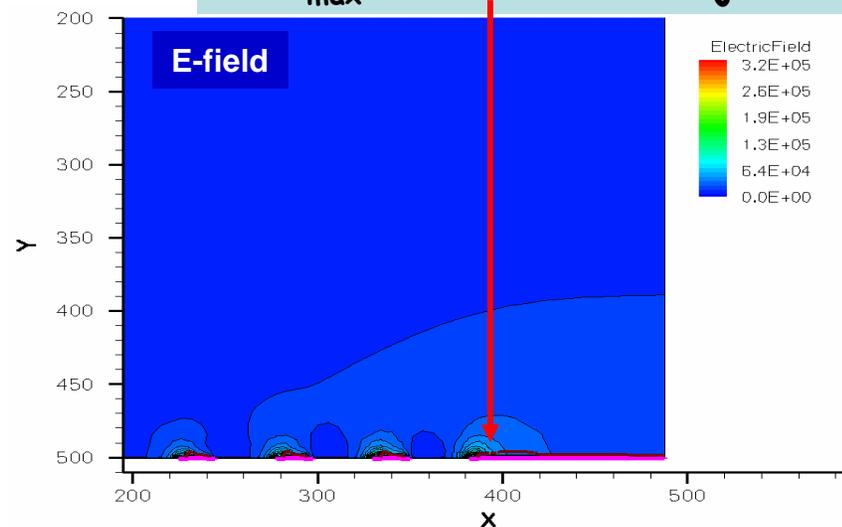
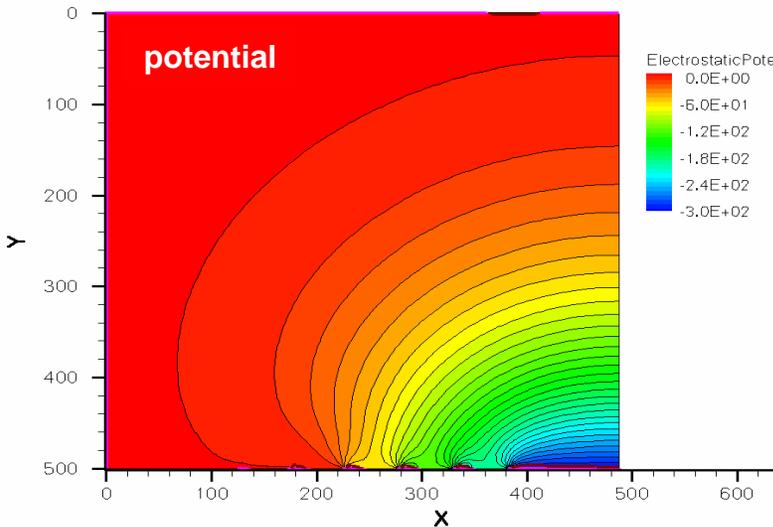


Break-down voltage vs. radiation damage

$N_{Ox} = 2 \cdot 10^{12} \text{cm}^{-2}$ $N_{it} = 0$ (~saturation value of N_{Ox} - sensor model I)

bias = V_0 , $V_1 = 0.75 \cdot V_0$, $V_2 = 0.5 \cdot V_0$, $V_3 = 0.25 \cdot V_0 \rightarrow$

- $V_{bd} = 300 \text{ V}$
- E_{max} @ curvature of junction

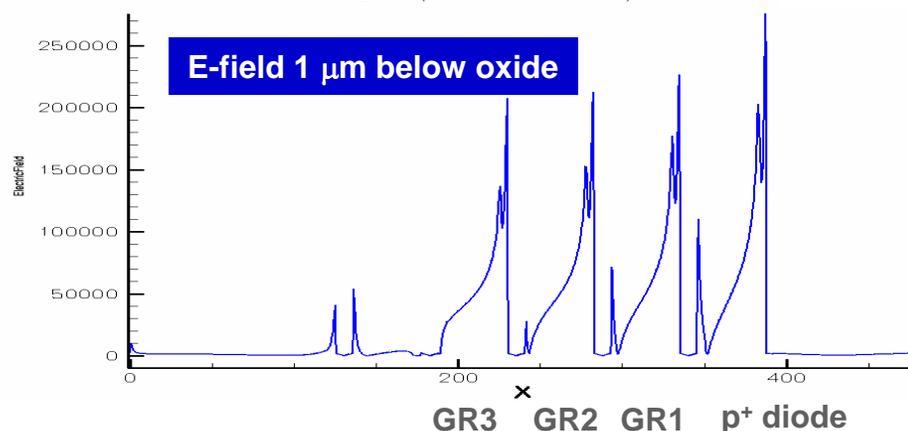
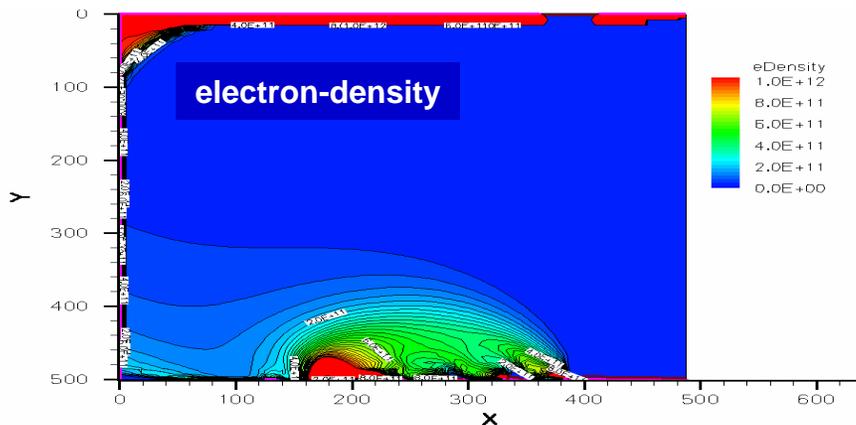
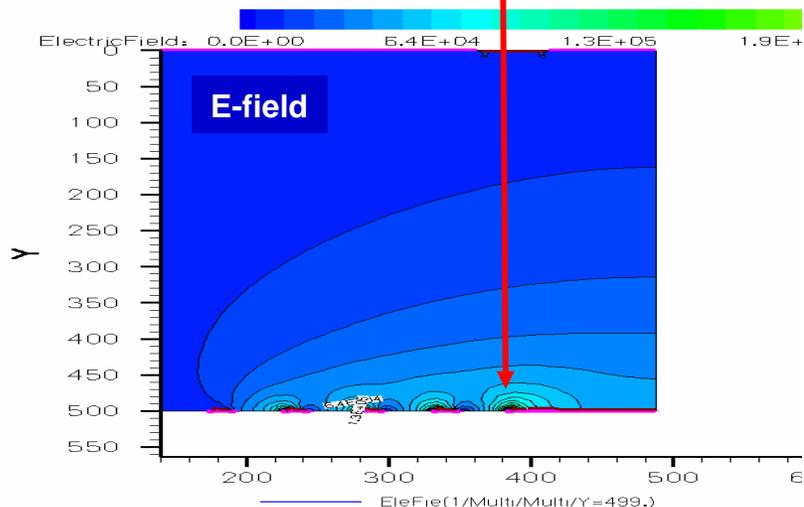
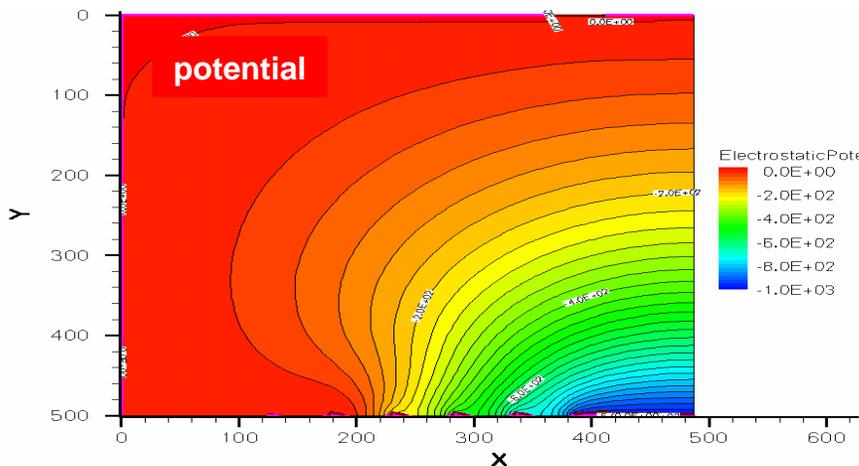


Break-down voltage vs. radiation damage (values found for high doses)

$N_{Ox}=2 \cdot 10^{12} \text{cm}^{-2}$; $N_{it}=4 \cdot 10^{12} \text{cm}^{-2}$ @ $E_c-E_{it}=0.35 \text{eV}$ and $4 \cdot 10^{13}$ @ 0.6 - acceptors)

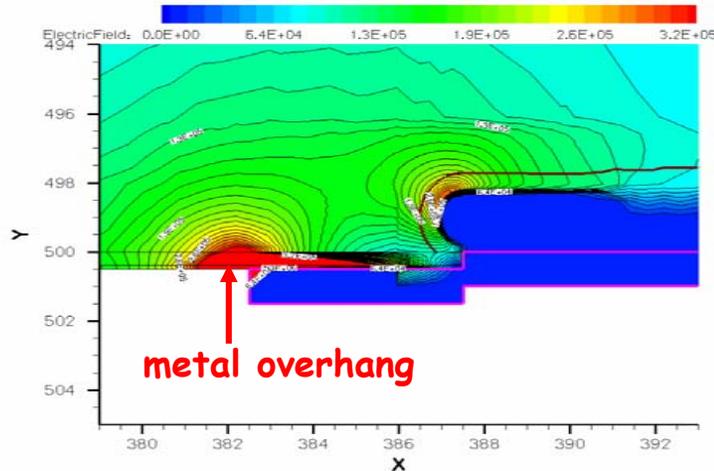
bias= V_0 , $V_1=0.75 \cdot V_0$, $V_2=0.5 \cdot V_0$, $V_3=0.25 \cdot V_0 \rightarrow$

- V_{bd} (break-down)= **995 V**
- E_{max} @ curvature of junction

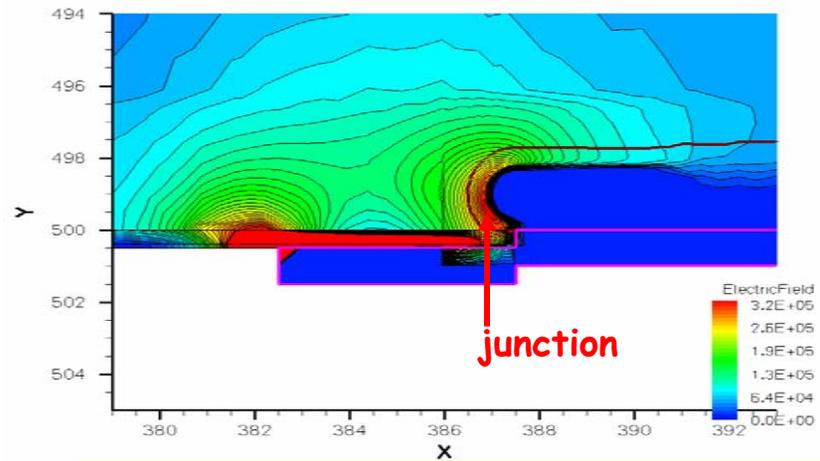


details of breakdown regions: E-field

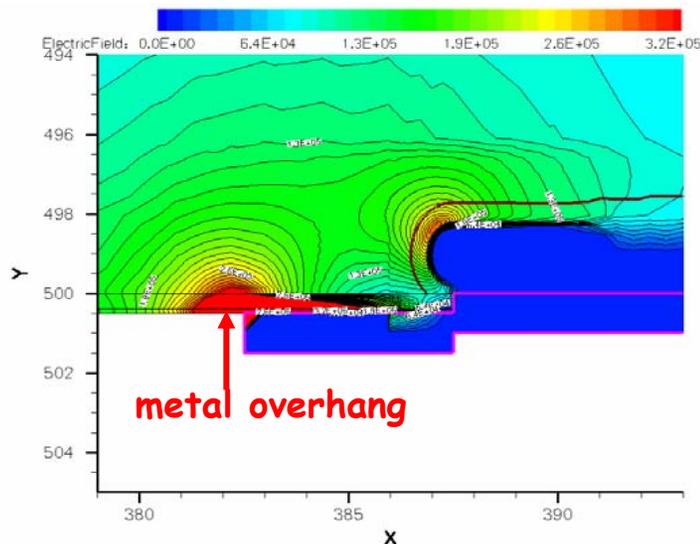
$N_{ox}=0, N_{it}=0 \rightarrow V_{bd} > 1000 V$



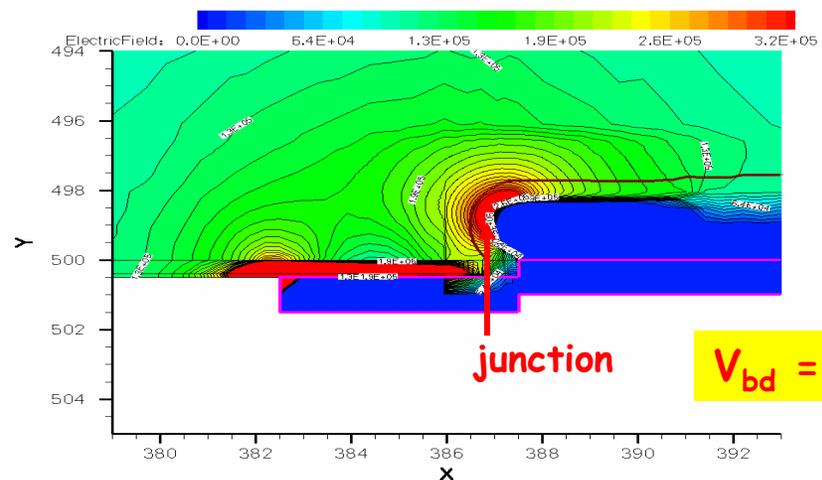
$N_{ox}=4 \cdot 10^{12} \text{ cm}^{-2}, N_{it}=0 \rightarrow V_{bd}=300 V$



$N_{ox}=2 \cdot 10^{12} \text{ cm}^{-2}, N_{it}=0 \rightarrow V_{bd}=690V$



$N_{ox}=2 \cdot 10^{12} \text{ cm}^{-2}, N_{it}=\text{acceptor } (4 \cdot 10^{12}, E_t=0.35\text{eV}), \text{ acceptor } (4 \cdot 10^{13}, E_t=0.6\text{eV})$



$V_{bd} = 995 V$

3. Next steps: Radiation damage and sensors simulations

3.1 Radiation damage measurements

- gated diodes under bias (under way)
- finish annealing studies (under way)
- segmented p⁺-n-sensor (characterization of unirradiated detector completed); ready for irradiation

Aim to complete work by end 2009

3.2 Simulations

- complete detailed comparison gated diodes ↔ simulations
- compare breakdown simulations for segmented detector(s) with measurements
- sensor design based on above experience

Aim to complete work by mid 2010

Characterisation segmented sensor:

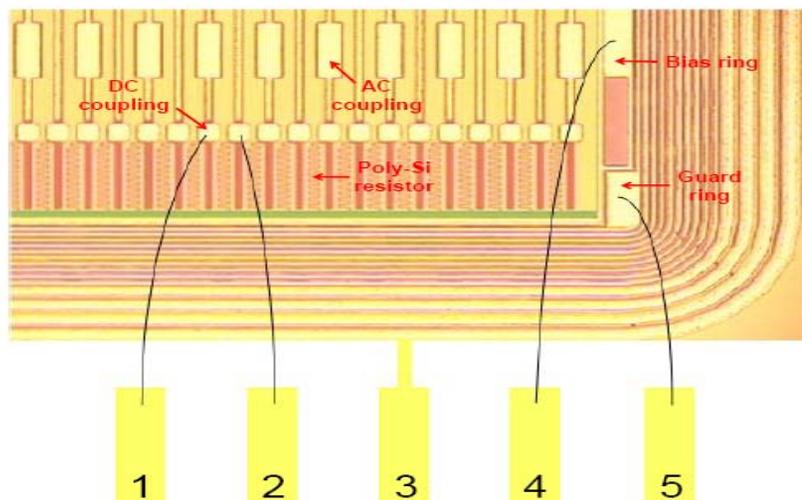
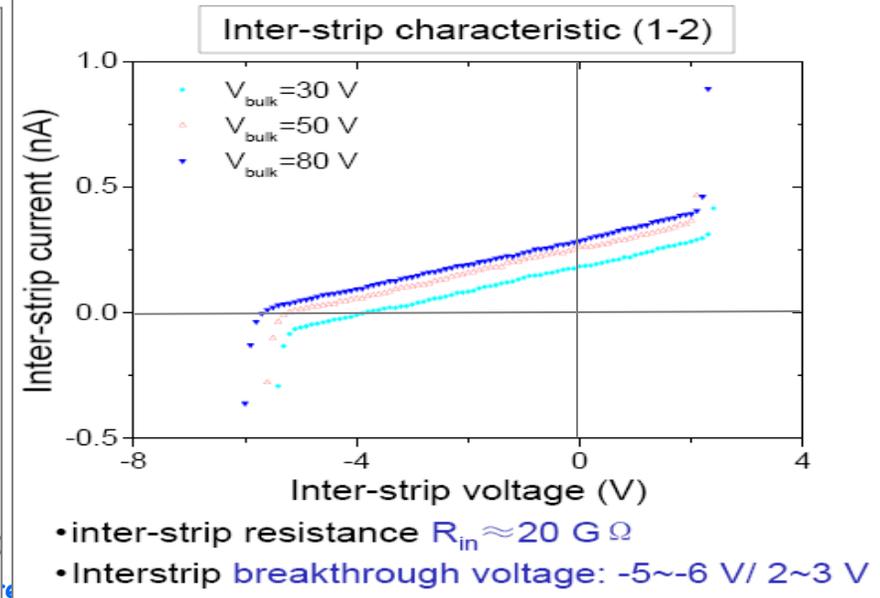
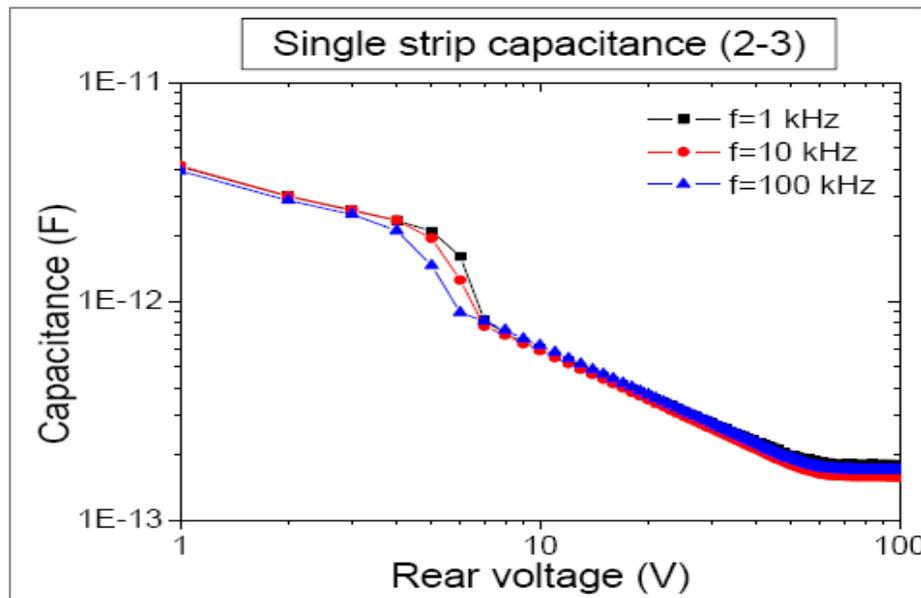
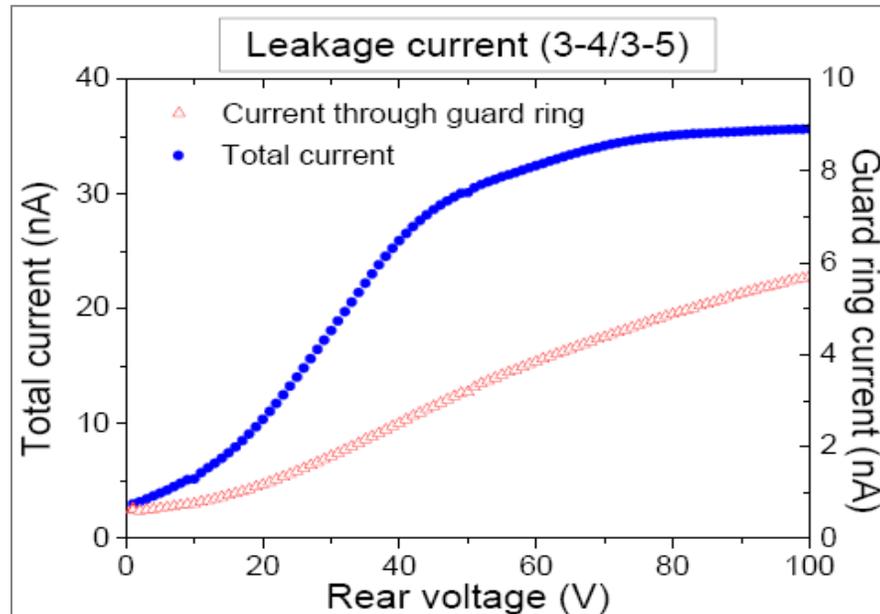


Fig. Photograph of microstrip sensor
Contacts: 1&2 – adjacent strips; 3 – rear plane; 4 – bias ring; 5 – 1st guard ring.



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